3D FPGA – The Path to ASIC-like Density, Power, and Performance

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Agenda

- The Logic Challenge
- Current FPGAs
- The Third Dimension
- Extension to other 3D applications
- > Summary



Transistors no Longer Dominate – Metal Interconnections Took Over

Interconnect Delay Creates the Timing Closure Problem

Delay (ps)



SYNOPSYS"

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As feature sizes shrink, chipmaking woes grow





Source: Mentor Graphics Corp.

Accelerating Mask-Set Cost !!!

Relative Increase of interconnection delay => More Metal Layers
 Increase in mask complexity => Mask cost increases

Process (μ)	2.0	 0.8	0.6	0.35	0.25	0.18	0.13	0.09	
Single Mask cost (\$K)	1.5	1.5	2.5	4.5	7.5	12	40	60	- 2,000
# of Masks	12	12	12	16	20	26	30	34	- 1,000
Mask Set cost (\$K)	18	18	30	72	150	312	1,000	2,000	0





Source: International Business Strategies

Number of IC Design Starts is Collapsing



Source: VLSI Research, Inc.



Semiconductor Market



Logic

2007

FPGA Aren't Substituting ASIC Total FPGA Market <\$3.5B, No Growth Since 2000



FPGA at ~\$4B Clearly didn't Fill the ASIC Gap FPGA market has barely grown in the last 5 years

FPGA cost-speed-power make it unattractive for many volume applications

- FPGA penalty is extremely high *
 - ➢ Gate Density: 1: 20-40
 - ➢ Power: 1: 9-12
 - > Speed: 1: 2-4

> Old Process ASIC is preferable in many applications

> Density ~1:32=> 5 process generations (45nm FPGA ~ 0.25μ ASIC)

- > => 3-4 gen. older ASIC process (0.13 μ -0.18 μ) is more competitive
- > => 3-4 gen. older ASIC process fab is fully deprecated and hence cheaper

> ASSP + Software in many cases provide a better alternative

*lan Kuon and Jonathan Rose, "Measuring the Gap Between FPGAs and ASICs", IEEE Transactions on Computer-Aided Design of Integrated Circuits and Systems (TCAD), Vol. 26, No. 2, pp 203-215, Feb. 2007



And Even Worse: Wire to Wire is Taking Over

Crosstalk: Big Problem at < 0.18µ Delay (ps) 70 Worst-case interconnect Cu 1.7μΩ-cm 60 delay due to Low k=2.0 Line 43µ long X-talk 50 .8µ thick 40 30 Interconnect 20 delay 10 150 650 500 350 250 180 100 70 (nm)

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The Tyranny of Interconnects

@100nm	@35nm	
30ps 6	100	
=		
5ps 1	1	
	,	
5	30	
1	1	
	@100nm 30ps 6 5ps 1	$ \begin{array}{cccccccccccccccccccccccccccccccccccc$

James Meindl director of the Microelectronics Research Center at the Georgia Institute of Technology By <u>Richard Goering</u> <u>EE Times</u> April 19, 2004 (5:00 PM EDT)



FPGAs see Diminishing Benefits with Scaling

- Over 90% of FPGA logic area penalty is due to programmable interconnect ('PIC')
- > Performance and power penalty are direct result of the area
- > Transistor as Programmable Interconnect doesn't scale well
- Scaling bring on "The Tyranny of Interconnects"
- Interconnect needs to increase faster than gate count to keep up (Rent's rule)
 - > ASIC adds metal layers with scaling
 - > PIC limiting factor is the single layer of diffusion shared with the logic.

=> FPGA moved from LUT4 to LUT6-7 as higher granularity logic cells reduce interconnections



Metal to Metal Antifuse Connectivity ~50x Denser than SRAM



Average area ratio of connectivity element ≈ 50



Antifuse Earlier Failure vs. SRAM FPGAs

- SRAM FPGAs were riding the bleeding edge of technology & getting one process node advantage
 Lesser Importance: Future scaling is expected to slow down
- > Re-programmability
 - Lesser Importance: Today even FPGA designs are verified by simulation rather than by trial and error
 - Innovation: Re-programmable antifuse technology
- High Voltage Programming and Isolation Transistors eat away the density advantage

> 3D Innovation: Programming circuits on another layer



Adding a Thin Crystallized Silicon Layer for the Primary Silicon





Foundation – Pre-fabricated High Voltage Programming Transistors ('Older' Process)





Primary Device ('House') on top of the Foundation





3D Antifuse Connectivity ~ ASIC Connectivity



Utilizing The Foundation for TSVs

- TSV + optional redistribution layers are fabricated in the base wafer ('Foundation') at low cost process
- Layer transfer "Smart Cut" to prepare the wafer for subsequent process
- TSV does not consume area of the expensive advanced-process silicon
- Inexpensive method for 3D stacks using TSVs



Using the Foundation for TSV





3D IC System with TSVs in the Foundations





3D Processor-DRAM Integrated Systems The solution to the "Memory Wall" Problem





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Through-DRAM TSVs* =>
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~5% Capacity Degradation

~5% Power Overhead



'Through-Foundation' TSVs =>
No DRAM Capacity Degradation
No Power Overhead
Better Processor Power Dissipation
DRAM design independent of Processor design



*Impacts of through-DRAM vias in 3D processor-DRAM integrated systems

Qi Wu; Rose, K.; Jian-Qiang Lu; Tong Zhang

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Thinned DRAM

3D System Integration, 2009. 3DIC 2009. IEEE International Conference on

Summary

- High density custom logic at reasonable NRE is crucial for the industry
- Interconnects are now dominating all logic devices
- > The Future is in the Third Dimension 3D

